IN THE CLAIMS:

1. (Currently Amended) Apparatus comprising

two walls defining a cavity having a cavity dimension, the cavity being configured so that the cavity dimension changes in response to electrostatic forces applied to the cavity, wherein the cavity dimension determines an optical response to light incident on the cavity, the optical response being based on interference, and

at least two electrical structures configured to apply electrostatic forces in the vicinity of the cavity, the electrical structures being independently controllable.

2. (Canceled).

3. (Canceled).

4. (Previously Presented) The apparatus of claim 2 in which the optical properties include reflectance.

5. (Previously Presented) The apparatus of claim 1 in which the two electrical structures comprise electrodes.

6. (Previously Presented) The apparatus of claim 1 in which the electrical structures lie on a wall of the cavity.

7. (Previously Presented) The apparatus of claim 6 in which the electrical structures lie side by side on the wall of the cavity.

8. (Canceled).

9. (Previously Presented) The apparatus of claim 1 in which changes in the cavity dimension that occur in response to the electrostatics forces are characterized by hysteresis.

10. (Previously Presented) The apparatus of claim 1 also including a second cavity adjacent to the cavity, the cavity and the second cavity sharing a common wall.

11. (Previously Presented) The apparatus of claim 1 also including stops within the cavity, the stops defining an intermediate cavity dimension between a minimum cavity dimension and a maximum cavity dimension.

12. (Previously Presented) The apparatus of claim 11 in which the stops define channels between them in which portions of a wall of the cavity lie in response to electrostatic forces.

13. (Previously Presented) The apparatus of claim 11 in which one of the electrical structures comprises electrodes embedded within the stops.

14. (Previously Presented) The apparatus of claim 11 in which the stops lie on a movable wall of the cavity.

15. (Previously Presented) The apparatus of claim 14 also including apertures in a second wall of the cavity configured to receive the stops.

16. (Previously Presented) The apparatus of claim 1 also including additional cavities having cavity dimensions, each of the cavities being configured so that its cavity dimension changes in response to electrostatic forces applied to the cavity, and additional electrical structures configured to apply electrostatic forces in the vicinities of the cavities, each of the additional cavities being associated with at least two of the additional electrical structures, the electrical structures with which each of the cavities is associated being independently controllable.

17. (Previously Presented) The apparatus of claim 16 in which at least some of the electrical structures associated with at least some of the respective cavities are coupled together.

18. (Previously Presented) The apparatus of claim 16 in which the cavities are organized in groups by coupling together of selected electrical structures.

19. (Previously Presented) The apparatus of claim 18 in which the coupling comprises bus conductors.

20. (Previously Presented) The apparatus of claim 18 in which the coupling comprises bus elements fabricated on multiple levels of the apparatus.

21. (Previously Presented) Apparatus comprising

an array of interferometric modulators,

actuation electrodes associated with the respective interferometric modulators, and

a pattern of conductors connecting the actuation electrodes in groups.

22. (Previously Presented) The apparatus of claim 21 in which the groups comprise rows or columns of the actuation electrodes.

23. (Previously Presented) The apparatus of claim 21 in which the groups comprise pixels of a display.

24. (Previously Presented) The apparatus of claim 21 in which each of the interferometric modulators is associated with more than one of the electrodes.

25. (Previously Presented) The apparatus of claim 24 in which the pattern of conductors connects different ones of the electrodes associated with each of the interferometric modulators in a configuration that enables them to be energized independently.

26. (Previously Presented) The apparatus of claim 21 in which the electrodes are arranged on walls of cavities of the interferometric modulators.

27. (Currently Amended) A method comprising

energizing one electrical structure to apply an electrostatic force in the vicinity of a cavity[[,]]; and

independently energizing another electrical structure to apply an electrostatic force in the vicinity of [[a]]the cavity.

28. (Previously Presented) The method of claim 27 in which the one structure is energized to move an element of the cavity to a first position, and the other electrical structure is energized to maintain the element in the first position.

29. (Previously Presented) The method of claim 28 also including de-energizing the one structure while the other structure remains energized.

30. (Previously Presented) The method of claim 27 also including controlling the energizing of the one electrical structure and the other electrical structure to effect more than two optical states of the cavity.

31. (Previously Presented) The method of claim 27 also including energizing one electrical structure to apply an electrostatic force in the vicinity of each of multiple other

cavities, and independently energizing another electrical structure to apply an electrostatic force in the vicinity of each of the multiple other cavities.

32. (Previously Presented) The method of claim 31 also including controlling the energizing of the electrical structures to independently control the optical states of groups of one or more of the cavities.